

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

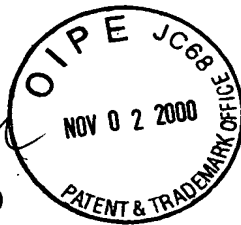
In re Application of:

Joseph S. HAYDEN *et al.*

Serial No.: 09/492,178 *Wm*

Filed: January 27, 2000

For: IMPROVED ION EXCHANGE TECHNOLOGY FOR FABRICATION OF
WAVEGUIDE SOURCE LASERS



Examiner: Unassigned

Group Art Unit: 2874

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R. Tallor

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, DC 20231

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NOV 06 2000

TECHNOLOGY CENTER 2800

Sir:

This Information Disclosure Statement is being submitted in connection with Applicants' continuing duty of disclosure under 37 C.F.R. §1.56.

This statement is being filed before the mailing date of the first office action on the merits in accordance with 37 C.F.R. §1.97(b) and, thus, no fee is required herein.

Listing of the References

See the attached form PTO-1449. Copies of the cited documents are attached.

Explanation of the Relevancy of the Cited Disclosures

All of the cited references are in the English language in accordance with 37 C.F.R. §1.98.

Respectfully submitted,

By: *John A. Sopp*

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